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REQUEST FOR

CONTINUED EXAMINATION (RCE)

TRANSMITTAL

Address to: **Commissioner for Patents**

Box RCE

Washington, DC 20231

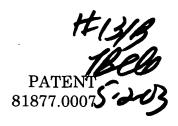
Application Number	09/670,917	/ 17 &		
Filing Date	September 29, 2000	He		
First Named Inventor	Norikazu MIZUNO, et al.	5-2		
Art Unit	2822			
Examiner Name	Maria F. Guerrero			
Attorney Docket Number	81877.0007			

This is a Request for Continued Examination (RCE) under 37 CFR 1.114 of the above-identified application. Request for Continued Examination (RCE) practice under 37 CFR 1.114 does not apply to any utility or plant application filed prior to June 8, 1995, or to any design application. See Instruction Sheet for RCEs (not to be submitted to the USPTO) on page 2.

1.	1. Submission required under 37 CFR 1.114								
a. b.	Previously submitt	ed		1.116 previoused). Sply Brief pre iii. Infe iv. Oth	usly filed on eviously filed on ormation Disclosure S er ed under 37 CFR 1.10	RECEIVED RECEIVED ANY -1 2003 CENTER (100) for a			
b.	period of months. (Period of suspension shall not exceed 3 months; Fee under 37 CFR 1.17(i) required)								
3. Fees The RCE fee under 37 CFR 1.17(e) is required by 37 CFR 1.114 when the RCE is filed. a. The Director is hereby authorized to charge the following fees, or credit any overpayments, to Deposit Account No. 50-1314 i. RCE fee required under 37 CFR 1.17(e) \$750 ii. Extension of time fee (37 CFR 1.136 and 1.17) \$930 04/29/2003 RHARIS1 00000077 501314 09670917 iii. Other 01 FC:1801 750.00 CH b. Check in the amount of \$									
SIGNATURE OF APPLICANT, ATTORNEY, OR AGENT REQUIRED									
Na	,	Ying Chen			No. (Attorney Agent)	50,193			
Sig	nature	1 4 5	<u> </u>	Date	April 21, 2003				
CERTIFICATE OF MAILING OR TRANSMISSION									
I hereby certify that this correspondence is being deposited with the United States Postal Service with sufficient postage as first class mail in an envelope addressed to: Commissioner For Patents, Box RCE, Washington, DC 20231, or facsimile transmitted to the U.S. Patent and Trademark Office on the date shown below.									
	me (Print Type)	Diane Zynn							
Sig	nature	Biane.	Zvan	Date	April 21, 2003				

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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of:

Norikazu MIZUNO, et al.

Serial No:

09/670,917

Filed: September 29, 2000

SEMICONDUCTOR DEVICE For:

> MANUFACTURING METHOD AND APPARATUS FOR REMOVING SILICON

NITRIDE FORMED IN A REACTION

CONTAINER WITH NF3 GAS FLOWING INTO THE REACTION CONTAINER (AS

TWICE AMENDED)

AMENDMENT

BOX RCE Commissioner for Patents Washington, D.C. 20231

Dear Sir:

Art Unit: 2822

Examiner: GUERRERO, M.

I hereby certify that this correspondence is being deposited with the United States Postal Service with sufficient postage as first class mail in an envelope addressed

Commissioner for Patents Washington D.C. 20231, on

April 21, 2003 Date of Deposit

Diane Zynn Name

04/21/03 Date

Signature

In response to the Final Office Action dated October 22, 2002, time for response to which has been extended by the enclosed Petition to April 22, 2003, please amend the above-referenced application as follows:

IN THE TITLE:

Please replace the title of the invention with the following text:

"SEMICONDUCTOR DEVICE MANUFACTURING METHOD AND APPARATUS FOR REMOVING SILICON NITRIDE FORMED IN A REACTION CONTAINER WITH NF3 GAS FLOWING INTO THE REACTION CONTAINER"